



Japan Information & Control TC Chapter Meeting Summary and Minutes

Japan Standards Spring 2014 Meetings Wednesday, April 16, 2014, 1:30 p.m. - 5:20 p.m. Conference Room 2, SEMI Japan, Tokyo

Next Committee Meeting

Friday, June 20, 2014, 1:30 p.m. - 5:00 p.m. Japan Standard Time Japan Summer Meetings 2014, Tokyo, Japan

Table 1 Meeting Attendees

Italics indicate virtual participants

Co-Chairs: Takayuki Nishimura (Dainippon Screen Mfg.), Mitsuhiro Matsuda (Hitachi Kokusai Electric) **SEMI Staff:** Chie Yanagisawa

Attendee: 11 + SEMI: 1

Company	Last	First	Company	Last	First
Canon Anelva	Sato	Mitsugu	Nippon Pulse Motor	Terasaki	Takashi
Dainippon Screen Mfg.	Nishimura	Takayuki	Tokyo Electron	Asakawa	Terry
Dainippon Screen Mfg.	Takasaki	Yoshihisa	Tokyo Electron	Mochizuki	Tadashi
Hitachi High-Technologies	Toyoshima	Yuko	Tokyo Electron	Murata	Naoko
Hitachi Kokusai Electric	Matsuda	Mitsuhiro	Tokyo Electron	Sakamoto	Mitch
Mitsubishi Electric	Seki	Seiji	SEMI Japan	Yanagisawa	Chie

* alphabetical order by company name

Table 2 Leadership Changes

Group	Previous Leader	New Leader
None		

Table 3 Ballot Results (or move to Section 4, Ballot Review)

Passed ballots and line items will be submitted to the ISC Audit & Review Subcommittee for procedural review.

Failed ballots and line items were returned to the originating task forces for re-work and re-balloting.

Document #	Document Title	Committee Action
5538A	New Standard: "Specification for Production Recipe Cache (PRC)"	Passed as balloted.

Table 4 Authorized Ballots (or move to Section 7, New Business)

#	When	SC/TF/WG	Details
None			

Table 5 Authorized Activities (or move to Section 7, New Business)

#	Туре	SC/TF/WG	Details
None			

Note: SNARFs and TFOFs are available for review on the SEMI Web site at: http://downloads.semi.org/web/wstdsbal.nsf/TFOFSNARF

Table 6 New Action Items (or move to Section 8, Action Item Review)

ltem #	Assigned to	Details
20140416-	Chie Yanagisawa	To require the revised North America Liaison Report, since there is no information of DDA
#1	(SEMI Japan)	TF, ESEC TF and SAN TF included on the report for this meeting.





Table 7 Previous Meeting Actions Items (or move to Section 8, Action item Review)

ltem #	Assigned to	Details
None		

1 Welcome, Reminders, and Introductions

Takayuki Nishimura (Dainippon Screen Mfg.), co-chair, called the meeting to order at 13:30. The meeting reminders on antitrust issues, intellectual property issues and holding meetings with international attendance were reviewed. Attendees introduced themselves.

Attachment: 01, Required Elements Reg_20130925_E+J

2 Review of Previous Meeting Minutes

The committee reviewed the minutes of the previous meeting held on December 6, 2013.

	To approve the minutes of the previous meeting held on December 6, 2013 with modifying the company's name from "Hitachi High Technologies" to "Hitachi High-Technologies" at the section of the meeting attendees.	
By / 2 nd :	Mitsuhiro Matsuda (Hitachi Kokusai Electric) / Yoshihisa Takasaki (Dainippon Screen Mfg.)	
Discussion:	n: None	
Vote:	9 in favor and 0 opposed. Motion Passed.	

Attachment: 02, 131206_Japan-ICC-Minutes_Final

3 SEMI Staff Report

Chie Yanagisawa (SEMI Japan) gave the SEMI Staff Report. This report contained information on the following items.

- Global SEMI Events
- Global Standards Meetings Schedule
- Ballot Critical Dates
- Publication Update
- Contact Information

Attachment: 03, SEMI Staff Report 2014 Apr._R0.1

4 Liaison Reports

4.1 North America Information & Control Committee

Mitsuhiro Matsuda (Hitachi Kokusai Electric) reported for the North America Information & Control Committee. This report contained information on the following items.

- Leadership
- Organization Chart
- Meeting Information
- Ballot Results
- Upcoming Ballots





- Task Force Reports
- Upcoming Meeting Schedule

Mitsuhiro Matsuda added the information of the ESEC TF as following.

- TF intends to shift the activity to the communication between equipment and component.
- TF plans to get the agreement with the SNARF and the amended TFOF through teleconference and then to propose them at the North America Information & Control TC Chapter meeting at SEMICON West 2014.

Attachment: 04, NA I&C report April 2014

4.2 Europe Equipment Automation Committee

Chie Yanagisawa (SEMI Japan) reported there was no update for Europe Equipment Automation Committee.

4.3 Taiwan Information & Control Committee

Chie Yanagisawa (SEMI Japan) reported there was no update for Taiwan Information & Control Committee.

4.4 Korea Information & Control Committee

The report was presented by Mitsuhiro Matsuda.

- Leadership
- Organization Chart
- Meeting Information
- Major Updates
- Task Force Updates

Attachment: 05, KR_I&C_liaison_20140320

5 Ballot Review

5.1 Document #5538A, New Standard: "Specification for Production Recipe Cache (PRC)"

Document #	Document Title	Committee Action
5538A	New Standard: "Specification for Production Recipe Cache (PRC)"	Passed as balloted.

Attachment: 06, Ballot Review for 5538A

6 Task Force Reports

6.1 Equipment Information System Security (EISS) Task Force

The task force leader, Mitch Sakamoto (Tokyo Electron), reported for the Equipment Information System Security Task Force. Of note:

- #5422A: New Standard: "*Guide for Equipment Information System Security*" was passed as balloted at the Japan Information & Control TC Chapter meeting on December 6. 2013 and is to be published as SEMI E169 shortly.
- The discussion on the future activity of the task force at the TC Chapter meeting on December 6. 2013 was reported as the attachment.

Attachment: 07, #EISS_TF_Report_140416+01





6.2 Fiducial Mark Interoperability Task Force

The task force co-leader, Mitsuhiro Matsuda (Hitachi Kokusai Electric), reported for the Fiducial Mark Interoperability Task Force as following.

- April 15, 2014: TF meeting
 - Approximately 20 attendees
 - o Shared and Discussed Document Draft #5604
 - 5604: Line Item Revision to SEMI M1-0114, Specification for Polished Single Crystal Silicon Wafer and SEMI M20-0110, Practice for Establishing a Wafer Coordinate System (Re: Addition of Notchless 450 mm Wafers)
 - o To be submitted feedback from TF members to "International Polished Wafer TF"
- To be discussed following items
 - o T7 Revision: Traceability related
 - o Positioning after Back Gridding: Assembly and Packaging related
 - o Reading Condition Report: I&C related
- Next meeting: TBD

Attachment: 08, 20140416FMI-TF-Report_r0

6.3 GEM 300 Task Force

The task force co-leader, Yoshihisa Takasaki, reported for GEM 300 Task Force. Of note:

- #5538A Specification for Production Recipe Cache mechanism
 - Submitted to Cycle 2 after confirmation on January 21
 - o Pre-adjudication on April 10 and Adjudication on April 15.
- #5600 revision to SEMI E5 E40the Removal of inconsistencies
 - 4 inconsistency is specified between E40 and E40.1
 - Ballot target is 2014 Cycle 3 or 4
- #5601 Wafer Object Modeling
 - Ballot target is early cycle in 2014

Attachment: 09, JA_GEM300TF Report_20140416_R1

6.4 JA I&CC Maintenance Task Force

The task force co-leader, Mitsuhiro Matsuda (Hitachi Kokusai Electric), reported for the JA I&CC Maintenance Task Force as following.

- #5615: Revision to SEMI E98-0309 "Provisional Standard for the Object-Based Equipment Model (OBEM)" and SEMI E98.1-1102 (Reapproved 0309) "Provisional Specification for SECS-II Protocol for the Object-Based Equipment Model"
 - Planed to submit 2014 Cycle 1 or Cycle 2, but it was postponed.
 - TF to be discussed balloting plan.
- 5 Years Review
 - o SEMI E153-0310 "Specification for AMHS SEM (AMHS SEM)"
 - The task force co-leader to ask the author Hiroshi Kondo (Murata Machinery) in order to check the document and to report action proposal to 5 year review.

Attachment: 10, 20140414JPMaintenanceTF-Report_r1





6.5 Predictive Carrier Logistics (PCL) Task Force

The task force co-leader, Terry Asakawa (Tokyo Electron), reported for the Predictive Carrier Logistics Task Force. Of note:

- Work on the revision of #5486 to #5486A:
 - New Standard: "Specification for Predictive Carrier Logistics (PCL)"
- Key discussions
 - How to model Carrier Logistics Job including predictions
 - How to control multiple CLJs
 - Preparation of scenario examples
- #5486A to be submitted for Cycle 3

Attachment: 11, PCL_TF_Report_2014_0416_R1.00

6.6 Sensor Bus Task Force

The task force leader, Hideaki Ogihara (Algo System), did not attend the meeting, so there was no report for Sensor Bus Task Force.

7 Old Business

None.

8 New Business

8.1 Chie Yanagisawa (SEMI Japan) commented that SEMI Japan planned to revise the SEMI Software Standards Textbook.

9 Action Item Review

9.1 Open Action Items

None.

9.2 New Action Items

ltem #	Assigned to	Details	
20140416-	Chie Yanagisawa	To require the revised North America Liaison Report, since there is no information of DDA	
#1	(SEMI Japan)	TF, ESEC TF and SAN TF included on the report for this meeting.	

10 Next Meeting and Adjournment

The next meeting of Japan Information & Control TC Chapter was scheduled as following.

Date and Time: Friday, June 20 13:30-17:00 Venue: JPR Conference Room 1, SEMI Japan, Tokyo

Having no further business, a motion was made by Takayuki Nishimura, co-chair, to adjourn the Japan Information & Control TC Chapter meeting at Conference Room 2, SEMI Japan. The meeting unanimously adjourned at 17:20.





Respectfully submitted by: Chie Yanagisawa Senior Standard Coordinator SEMI Japan Phone: +81.3.3222.5863 Email: cyanagisawa@semi.org

Minutes approved by:Takayuki Nishimura (Dainippon Screen Mfg.), Co-chairJune 6, 2014Mitsuhiro Matsuda (Hitachi Kokusai Electric), Co-chairJune 2, 2014

Table 8 Index of Available Attachments #1

#	Title	#	Title
01	Required Elements Reg_20130925_E+J	07	#EISS_TFReport_140416+01
02	131206_Japan-ICC-Minutes_Final	08	20140416FMI-TF-Report_r0
03	SEMI Staff Report 2014 AprR0.1	09	JA_GEM300TF Report_20140416_R1
04	NA I&C report April 2014	10	20140414JPMaintenanceTF-Report_r1
05	KR_I&C_liaison_20140320	11	PCL_TF_Report_2014_0416_R1.00
06	Ballot Review for 5538A		

#1 Due to file size and delivery issues, attachments must be downloaded separately. A .zip file containing all attachments for these minutes is available at www.semi.org. For additional information or to obtain individual attachments, please contact [SEMI Staff Name] at the contact information above.